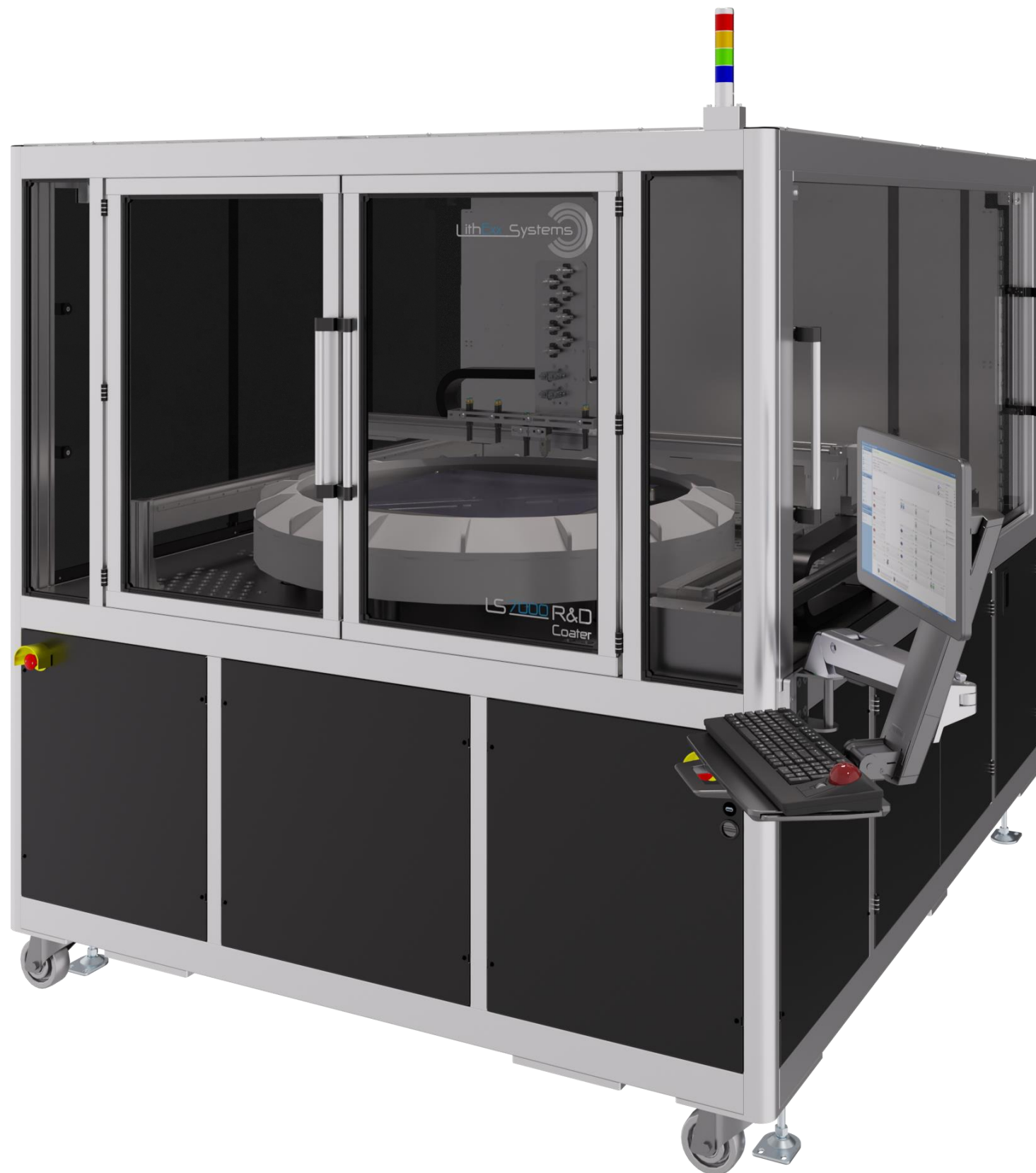


LS 7000 – Coater and Developer Systems



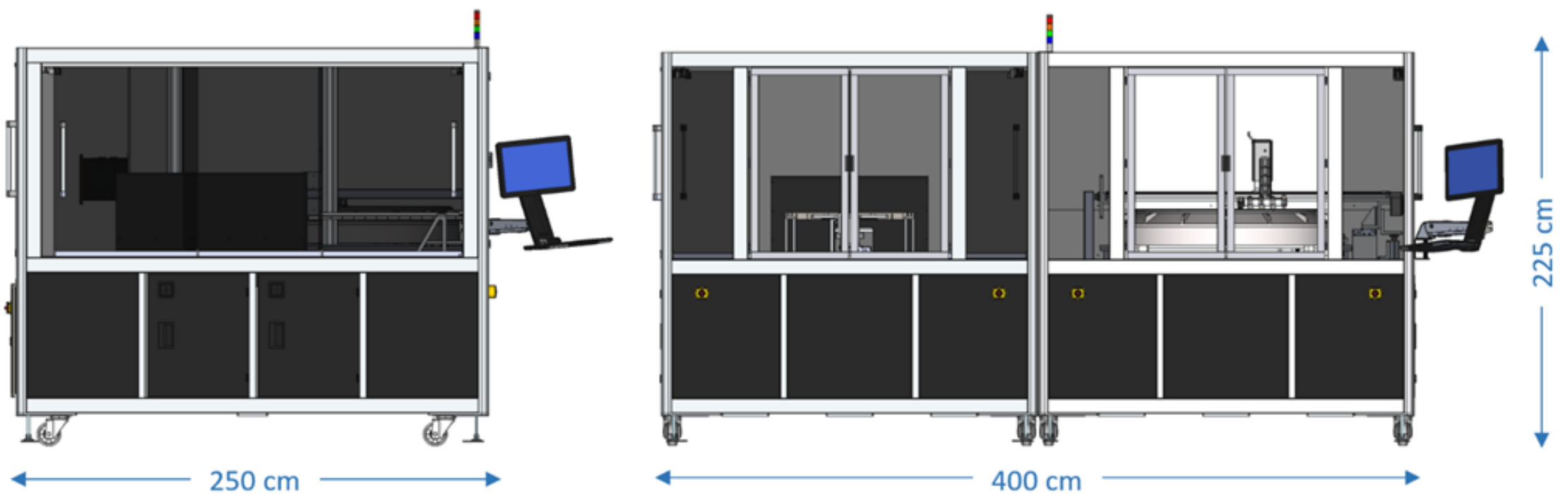
LS 7000 Systems are designed for large substrates with diagonals up to 1000mm

LS 7000 Systems are available as R&D-tool with manual handling and as full automated production tools for various applications such as spray coating, puddle - or spray developing, bake processes and others. This system has the capability to process substrates with diagonals up to 1000mm.

System Features

- 2 IO Stations for substrate specific cassettes
- Spray coating- /developing modules for round and square substrates
- Binary nozzles for spray coating of positive resists, polyimides and PBOs
- Developer systems for positive resist and photosensitive polyimides and PBOs
- Hotplate stack for up to 4 hotplates (200°C)
- 3 link-robot handling system for substrates up to 15kg with diagonals up to 1000mm
- System footprint 2.0m x 2.5m (manual tool module)
- Flexible software

LS 7000 – Coater and Developer Systems



Robot Handling System

- Automated robot handling system for substrates with diagonals up to 1000mm and weight up to 15kg
- Endeffectors for various substrate types and sizes
- Contactless substrate centering
- IO-stations with integrated cassette detection, slot scanning and barcode reader



Coater Module

- Process chamber for substrates with diagonals up to 1000mm
- Servo motor driven dispense arm with x-, y- and z-axes
- Sophisticated spray nozzles for application of Photoresists, Polyimides, PBOs
- Unique EBR (edge bead removal) system for square substrates
- Automated chuck cleaning function
- Spin motor 1000 ± 0.5 rpm
- Programmable bowl- and topside rinse (for prewet and cleaning)
- Vacuum chuck with backside protection
- Symmetrical process cup exhaust with exhaust control
- Media drawer with leakage sensors



Developer Module

- Process chamber for substrates with diagonals up to 1000mm
- Servo motor driven dispense arm with x-, y- and z-axes
- Puddle- or spray nozzles for development and rinse mounted on servo motor driven arm
- Development systems for TMAH-based as well as for solvent-based developer media available
- Automated chuck cleaning function
- Spin motor 1000 ± 0.5 rpm
- Programmable bowl- and backside rinse
- Chuck with sophisticated substrate holder
- Symmetrical process cup exhaust with exhaust control
- Media drawer with leakage sensors



Hot- and Coolplate Module

- Hotplates $60^{\circ}\text{C} - 200^{\circ}\text{C}$ for substrates sizes up to 700mm x 700mm
- Thermal isolated heating plate with 4 separate heating zones
- Heated hotplate cover – temperature separately programmable
- Servomotor controlled proximity pins
- Proximity distance between substrate and hotplate programmable via recipe
- Fixed stop pins ($150\mu\text{m}$)
- Programmable N₂- and CDA-purge with electronic flowmeter
- Adjustable exhaust with monitoring

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